PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of Confirmation No.: 5877

Kenichi MORIMOTO Art Unit: 1763

S. N. 10/737,393 Examiner: Allan W. Olsen

Filed: December 16, 2003

For: MASK BLANK FOR CHARGED PARTICLE BEAM EXPOSURE, METHOD OF FORMING MASK BLANK AND MASK FOR CHARGED PARTICLE BEAM EXPOSURE

RESPONSE TO OFFICE ACTION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the office action dated December 14, 2005, for which a three month extension of time is requested to exend the period for response to June 14, 2006, please make the following amendments:

Claim amendments begin on page 2 of this document.

Remarks begin on page 4 of this document.